Claims

1. Device for drying disc-shaped substrates comprising
   an elongated body having a top surface, a bottom surface and a circumferential surface,
   comprising a hole in the top surface forming a channel which extends to a lower drainage part (B) of the elongated body and having a depth (L1) and being chamfered having a conical angle (α) forming an edge between the channel and top surface and forming a conical recess suitable for resting a disc shaped substrate, wherein the conical angle is more than 10° and less than 30° and that the depth (L1) is more than 6 mm and less than 12 mm.

2. Device according to claim 1 characterized in that
   the material used for the device comprises ceramic filled polyetheretherketone (CFM PEEK).

3. Device according to any of claim 1 or claim 2, characterized in that
   the edge between chamfer and top surface is rounded with a radius not more than 0.1 mm and not less than 1 mm.

4. Device according to any of claims 1 to 3, characterized in that
   the diameter of the channel is not less than 0.5mm and not more than 3mm,
   preferably not less than 0.8mm and not more than 1.2mm.

5. Device according to any of claims 1 to 4, characterized in that
   the length of the channel (L2) is not less than 30 mm.

6. Method of drying a disc-shaped substrate using a device according to any of claims 1 to 5.